

# 12吋智慧終端離子性蝕刻機 (Ion Beam Etcher IBE Etcher)

製程能力



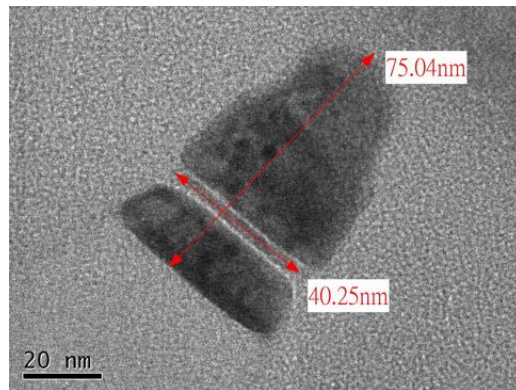
## 製程能力

- STT & SOT MTJ structure Etching
- 提供矽基板上之Co、Pt、CFB、MgO...等磁性記憶體結構層的蝕刻，總厚度小於50nm以下。

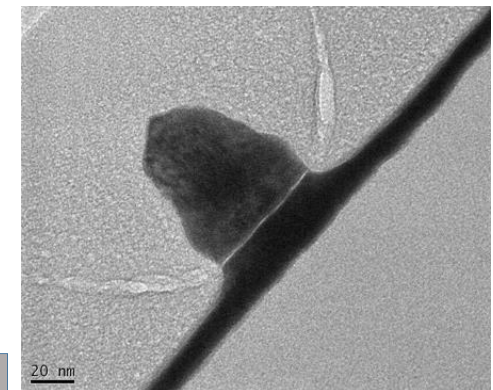
## 晶片尺寸

- 8吋、12吋
- 破片、4吋、6吋 (Can't be detected by OES.)

STT MTJ structure

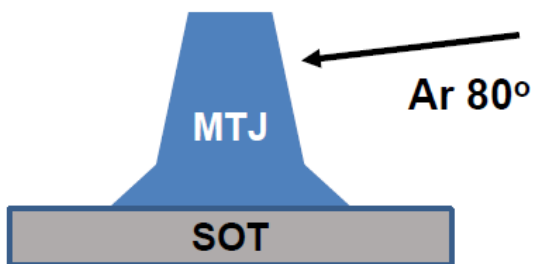


SOT MTJ structure

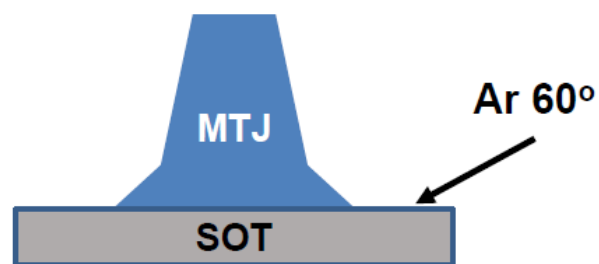


# IBE Etching Flow for MTJ Structure

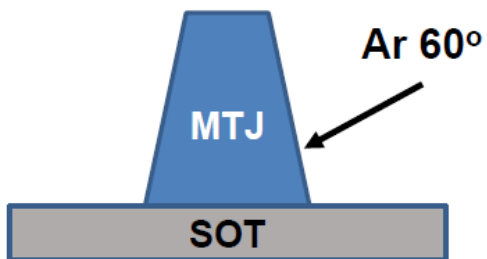
## 1. MTJ main etch & trimming



## 2. Clean SOT surface



## 4. Sidewall cleaning



## 3. Eliminate footing

